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Substitute for form 1449A/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)				Complete if Known	
				Application Number	10/029,080
				Filing Date	December 21, 2001
				First Named Inventor	Nanaji Saka
				Group Art Unit	To be Assigned
				Examiner Name	To be Assigned
Attorney Docket Number	A-69174-1/MSS				
Sheet	1	of	3		

U.S. PATENT DOCUMENTS						
Examiner Initials*	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
MJ		4,959,113		John V. H. Roberts	September 25, 1990	
AS		5,069,002		Sandhu, et al.	December 3, 1991	
AS		5,433,651		Lustig, et al.	July 18, 1995	
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AS		5,672,091		Takahashi, et al.	September 30, 1997	
AS		5,676,587		Landers, et al.	October 14, 1997	
AS		5,770,103		Wang, et al.	June 23, 1998	
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AS		5,838,448		Aiyer, et al.	November 17, 1998	
AS		5,840,629		Roanld A. Carpio	November 24, 1998	
AS		5,897,375		Watts, et al.	April 27, 1999	
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AS		5,953,115		William Francis Landers	September 14, 1999	
AS		5,954,997		Kaufman, et al.	September 21, 1999	
AS		5,964,643		Birang, et al.	October 12, 1999	
AS		5,964,653		Perlov, et al.	October 12, 1999	

FOREIGN PATENT DOCUMENTS								
Examiner Initials*	Cite No. ¹	Foreign Patent Document			Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Office ³	Number ⁴	Kind Code ² (if known)				
AS		EP	0881484	A2	LAM Research Corporation	02 December 1998		
AS		WO	99/02304	A1	Applied Materials, Inc.	21 January 1999		

Examiner Signature	Michael Stefan	Date Considered	4-15-03
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		Group Art Unit	To be Assigned		
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		Number	Kind Code ² (if known)			
W		5,972,787		Boggs et al.	October 26, 1999	RECEIVED MAR 22 2001 TECHNOLOGY CENTER 2001
W		5,985,679		Michael J. Berman	November 16, 1999	
W		5,985,748		Watts, et al.	November 16, 1999	
W		6,001,730		Farkas, et al.	December 14, 1999	
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W		6,036,587		Tolles et al.	March 14, 2000	
W		6,046,111		Karl M. Robinson	April 4, 2000	
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W		6,062,133		Guy Blalock	May 16, 2000	
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W		6,063,306		Kaufman, et al.	May 16, 2000	
W		6,068,539		Bajaj, et al.	May 30, 2000	
W		6,068,549		Paul Jackson	May 30, 2000	
W		6,071,177		Lin, et al.	June 6, 2000	
W		6,074,287		Miyaji, et al.	June 13, 2000	
W		6,077,452		Herbert E. Litvak	June 20, 2000	
W		6,179,956	B1	Nagahara, et al.	January 30, 2001	
W		6,204,922	B1	Scott A. Chalmers	March 20, 2001	
W		6,238,590	B1	Fischer, et al.	May 29, 2001	
W		6,257,953	B1	Gitis, et al.	July 10, 2001	
W		6,290,584	B1	Kim, et al.	September 18, 2001	

Examiner Signature	<i>Michael Stofie</i>	Date Considered	4-15-03
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		First Named Inventor	Nanaji Saka
		Group Art Unit	To be Assigned
Examiner Name	To be Assigned	Attorney Docket Number	A-69174-1/MSS
Sheet	3	of	3

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
MS		Adams, et al., "Process Control and Endpoint Detection with Fullscan ISRM System in Chemical Mechanical Polishing of Cu Layers," CMP-MIC, March 2000, 5 pages	
MS		Bonner et al., "Removal Rate, Uniformity and Defectivity Studies of Chemical Mechanical Polishing of BPSG Films," MRS, Spring 2000, 6 pages	
MS		Garretson et al., "New Pad Conditioning Disk Design Delivers Excellent Process Performance While Increasing CMP Productivity," CMP Technology for ULSI Interconnection, SEMICON West 2000, 9 pages	
MS		Osterheld et al., "A Novel Retaining Ring in Advanced Polishing Head Design for Significantly Improved CMP Performance," MRS, April 5-9, 1999, 8 pages	
MS		Römer et al., "STI CMP Using Fixed Abrasive Demands, Measurement Methods and Results," CMP-MIC, March 2000, 10 pages	
MS		Surana et al., "Defectivity Reduction in Copper CMP Processes," VMIC, June 2000, 3 pages	
MS		Tang, et al., "Novel Integrated Single Wafer Immersion Megasonics for Advanced Post CMP Cleaning in a Next Generation Dry-in Dry-out CMP System," CMP-MIC, March 2000, 5 pages	

Examiner Signature	Michael Stefan	Date Considered	4-15-03
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